

# Tailoring Mechanical Properties of a-C:H:Cr Coatings

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**Additional information regarding experiments:**

*XPS spectra:*

XPS depth profiling maps illustrate for a-C:H:Cr coatings show the presence of each element versus the etching time. The color reveals the intensity of the signal (yellow = high number of counts). One can see that a higher amount of oxygen is obvious in floating mode.

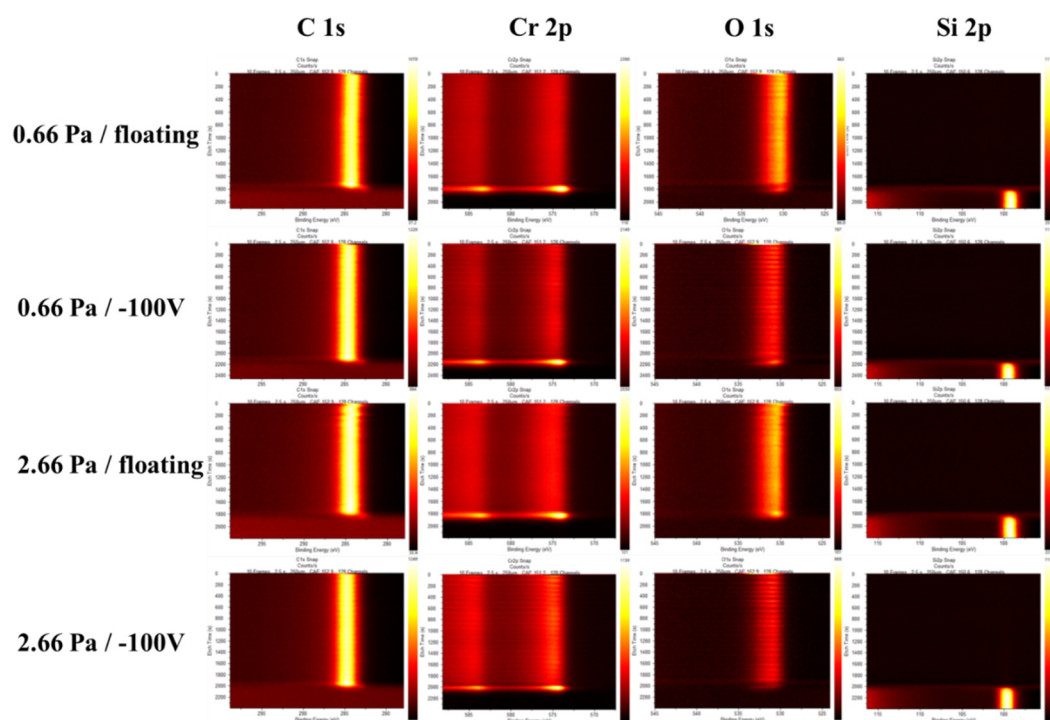


Figure S 1. XPS depth profiling maps illustrate for a-C:H:Cr coatings show the presence of each element versus the etching time.